



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: John L. Fulton, et al.

Serial No: 10/783,249

Filed: 2/19/2004

For: PROCESS AND APPARATUS FOR
REMOVING RESIDUES FROM
SEMICONDUCTOR SUBSTRATES

) Art Unit: 1746

)

) Examiner: Michail Kornakov

)

) File No: 14138-J

)

) Date: February 8, 2005

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INFORMATION DISCLOSURE STATEMENT

(References – See attached forms PTO/SB/08A and PTO/SB/08B)

Mail Stop Amendment
Commissioner for Patents
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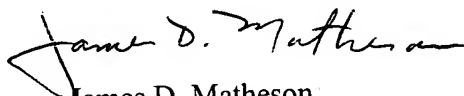
Attached hereto are Forms PTO/SB/08A and PTO/SB/08B listing documents believed to be relevant to the subject application. It is respectfully requested that these documents be considered by the examiner and an initialed copy of each form be returned to the undersigned.

This disclosure statement should not be construed as a representation that a search has been made or that no other material information exists, as defined in 37 C. F. R. § 1.56(a). No admission is made regarding whether any of the submitted references is prior art.

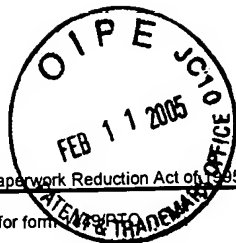
It is believed that this disclosure complies with the requirements of 37 C. F. R. §§ 1.56, 1.97, 1.98, and the Manual of Patent Examining Procedures § 609. If for some reason the examiner considers otherwise, it is respectfully requested that the undersigned be called so that any deficiencies can be remedied.

This IDS is either being submitted within the 3 month deadline or prior to the 1st Office Action, and no fees are believed to be required. However, if any fees are required for consideration of this paper, the Director is hereby authorized to charge our Deposit Account No. 02-1275.

Respectfully submitted,


James D. Matheson
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PTO/SB/08A (08-03)

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Sheet 1 of 9

Complete if Known

Application Number	10/783,249
Filing Date	02/19/2004
First Named Inventor	John L. Fulton
Art Unit	1746
Examiner Name	Michail Kornakov
Attorney Docket Number	14138-J

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
		US- 5,470,802	11-28-1995	Gnade et al.	
		US- 5,488,015	01-30-1996	Havemann et al.	
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		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
		JP02001122	6/9/1988	Matsushita Elec		
		JP02113525	10/24/1988	Matsushita Elec		
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		JP02098928A2	10/05/1988	Tokyo Electron		
		JP03261128A2	03/09/1990	Sumitomo Seika		

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Sheet 2 of 9**Complete if Known**

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		EP 0 688 052 A3	08-28-1996	Shin-Puu Jeng		

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		EP 0 733 269 B1	01-16-2002	L.T. Canham		
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		EP 0 992 852 A2	04-12-2000	Nippon Telegrap		
		EP 1 024 524 A2	01-25-2000	Kiyoyuki Morita		

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First Named Inventor

John L. Fulton

Art Unit

1746

Examiner Name

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NON PATENT LITERATURE DOCUMENTS

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		YEE, G.G., et al., Fourier Transform Infrared Spectroscopy of Molecular Interactions of Heptafluoro-1-butanol or 1-Butanol in Supercritical., J. Phys Chem 1992, 96, 6172-6181	
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Inventor: John L. Fulton, et al.

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) Examiner: Michail Kornakov

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For: PROCESS AND APPARATUS FOR
REMOVING RESIDUES FROM
SEMICONDUCTOR SUBSTRATES

) Date: February 8, 2005

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